

List of reference symbols

- 1 semiconductor substrate
- 2 first trench
- 5 3 oxidized silicon layer
- 4 aluminium-oxide layer
- 5 horizontal regions
- 6 second trench
- 7 widened second trench
- 10 8 bottle structure
- 9 first electrode
- 10 dielectric layer
- 11 conductive filling
- 12 rugged polysilicon layer
- 15 13 first silicon nitride layer
- 14 silicon nitride layer
- 15 hardmask
- 16 process window